

Insertion Devices



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Outline

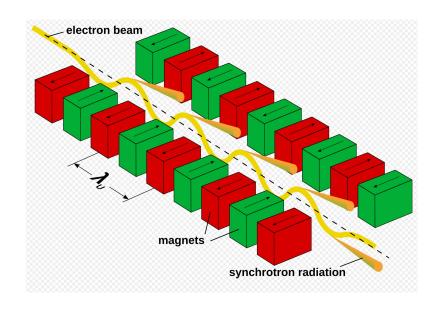
- Insertion devices to generate radiation
- Types of Insertion devices
- Undulators torwards the future
- Try to design an undulator?



What is an insertion device?



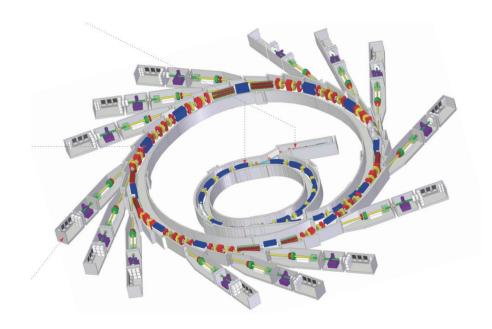
An **insertion device** (**ID**) is a component in modern synchrotron light sources, so called because they are "inserted" into accelerator tracks. They are periodic magnetic structures that stimulate highly brilliant, forward-directed synchrotron radiation emission by forcing a stored charged particle beam to perform wiggles, or undulations, as they pass through the device. This motion is caused by the Lorentz force, and it is from this oscillatory motion that we get the names for the two classes of device, which are known as wigglers and undulators. As well as creating a brighter light, some insertion devices enable tuning of the light so that different frequencies can be generated for different applications.



Key words: synchrotron radiation\periodic magnet structure\inserted\tuning light



Introduction: synchrotron radiation source and IDs

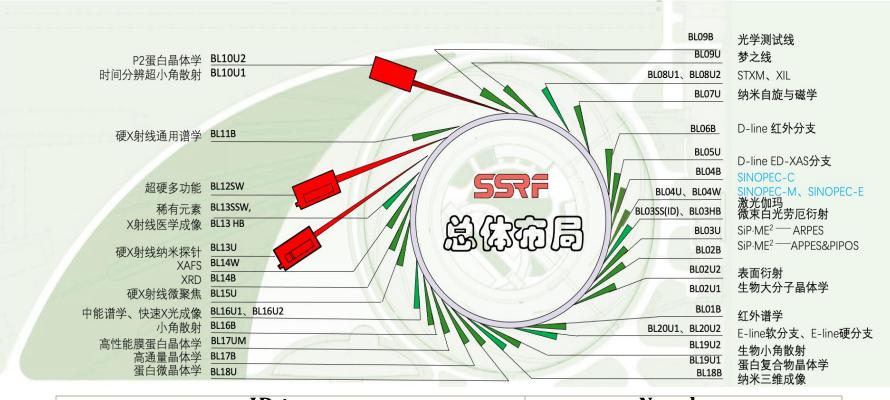




- The synchrotron radiation source consists of an electron linear accelerator, an electron booster and an electron storage ring.
- Special magnets that are specifically designed to generate synchrotron radiation
- They are quite literally devices that are inserted into an accelerator straight section (drift space)
- Two basic types; Undulators and Wigglers
- Periodic, sinusoidal magnetic field



SSRF and SSRF-II



ID type	Number
IVU	12
CPMU	4
Wiggler	3
EPU	4 (+2)
AppleKnot EPU	1
SCW	1



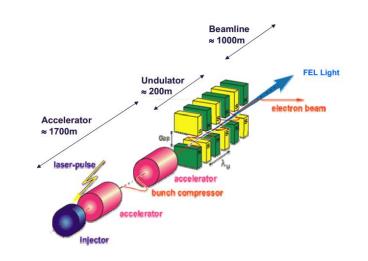
Introduction: FEL facility and undulators

- Free electron laser is a kind of high brightness coherent synchrotron radiation, its brightness can be 9 orders of magnitude higher than the third generation synchrotron radiation.
- In order to achieve saturation of the output power of the high gain free electron laser, tens or even hundreds of meters of undulators are needed.
- At present, Europe, the United States, Japan, South Korea and other countries have built hard X-ray free electron laser devices.
- A total length of 3.2 kilometers, the Shanghai high refrequency hard X-ray free electron laser device (SHINE) is under construction, and the first phase will be the construction of three 300-meter-long undulator lines.





LCLS-I and LCLS-II

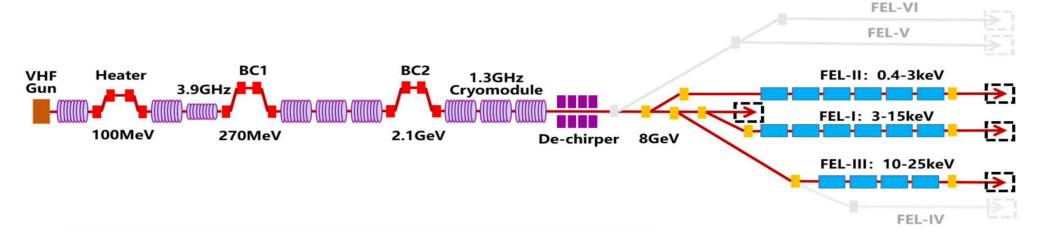


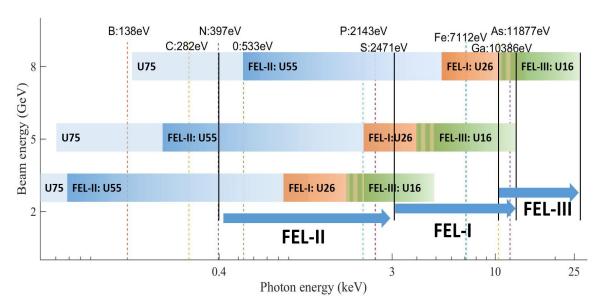


SHINE project (3.2km long)



SHINE undulator project





Location	equipments	quantity
Injector	Laser Heater U50, 0.5m	1
FEL-I	Planner U26, 4m	42
	Phase Shifter -U26, 4m	41
FEL-II	Planner U,2.2m	2
	Planner U55, 4m	18
	Phase Shifter -U55	35
	Double Planner U55&U75, 4m	14
	EPU,4m	4
FEL-III	Superconduct Uudulator ,4m	40
	Phase Shifter -U16	39

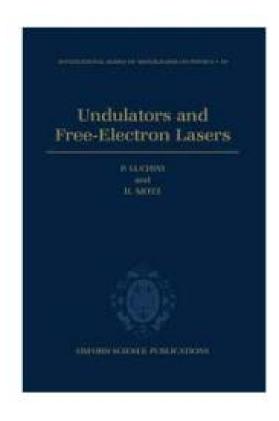


Reference Books of IDs

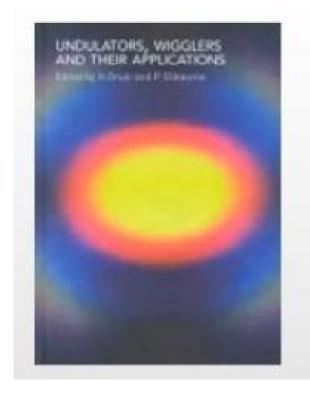


J. A. Clarke: "The Science and Technology of Undulators and Wigglers" Oxford University Press, 2004

Referred to as "Clarke"



P. Luchini, A. Motz: "Undulators and Free Electron Lasers" Clarendon Press, Oxford



H. Onuki. P. Elleaume: "Undulators, Wigglers and their Applications Taylor & Francis, New York 2003

Referred to as "Onuki"



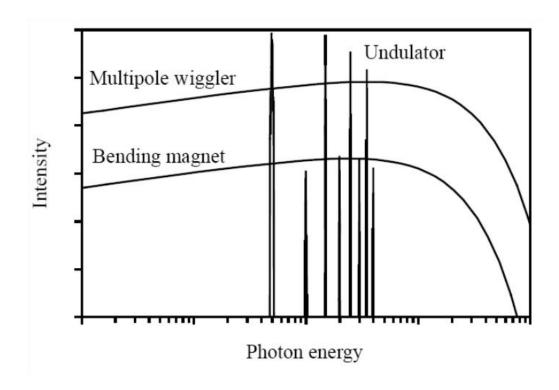
Computer codes for undulator/wiggler radiation

Radiation calculation including emittance and energy spread

Name	Authors	Platform	Download
B2E & SRW	O. Chubar, P. Elleaume, ESRF	Mac, Windows	http://www.esrf.fr/machine/grou ps/insertion_devices/Codes/soft ware.html
URGENT	R.P. Walker, Diamond Light Source	Fortran Source	Contact Author
XOP	M. Sánchez del Río, ESRF & R. J. Dejus, APS	Unix, Windows	http://www.esrf.fr/computing /scientific/xop/
SPECTRA	T. Tanaka, SPring8	Unix, Windows Mac	https://spectrax.org/spectra/

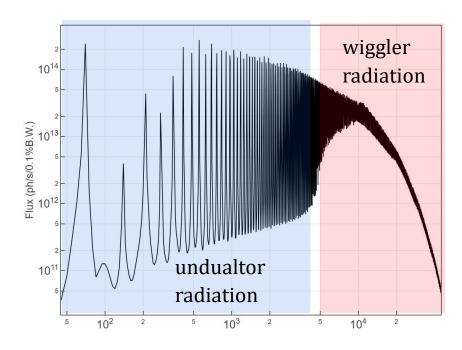


Typical Spectrum of the Three Sources





Researchers typically only use one photon energy or wavelength at a time (they use a monochromator to select this wavelength) for their experiments undulators, which have the highest intensities, are the most popular sources of SR



3.5GeV, 200mA, Period 100mm,K=5.6



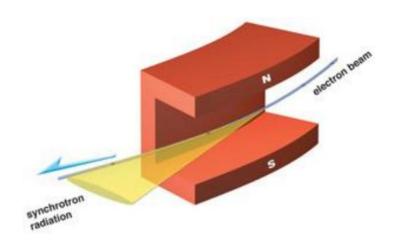
SR from Dipoles

A bending magnet or dipole has a uniform magnetic field

The electron travels on the arc of radius set by the magnetic field strength

Horizontally the light beam sweeps out like a lighthouse - the intensity is flat with horizontal angle

Vertically it is in a narrow cone of angle typically $\pm 1/\gamma$



$$V \approx E/E_o$$
 $\epsilon_c = 665E^2B$

The critical energy is given (in eV)by where E is expressed in GeV and B is in Tesla and so in more practical units



SR Power

The average SR power is very high and the power density is even higher

The total power emitted by the electron beam in the dipoles is

$$P_{\text{total}} = 88.46 \, \frac{E^4 I_b}{\rho_0}$$

where the power is in **kW**, E is in GeV, I_b is in A, bend radius is ρ_0 in m. and **power density on axis** (in W/mrad²)

$$\left. \frac{dP}{d\Omega} \right|_{\psi=0} = 18.08 \, \frac{E^5 I_b}{\rho_0}$$



Insertion Devices Power

The total power emitted by a beam of electrons passing through any magnet system is

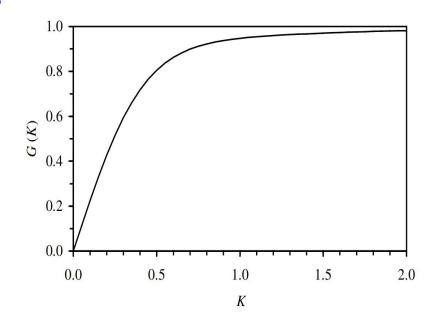
$$P_{\text{total}} = 1265.5 E^2 I_b \int_0^L B(s)^2 ds$$

For a sinusoidal magnetic field, wiggler and undulator, the total power emitted is (in W)

$$P_{\text{total}} = 632.8 \, E^2 B_0^2 L I_b$$

Power density

$$\frac{dP}{d\Omega}\Big|_{\psi, \theta=0} = 1012.5 \, \frac{E^4 B_0^2}{K} L I_b G(K)$$





Power Examples

The RF system must replace this lost power continuously to keep the electrons in an equilibrium state

Dipoles

Light Source	Energy(GeV)	C (m)	Current (mA)	P_total (KW)	SR loss/turn, dipole (KeV)
HEPS	6	1360.4	200	578.4	2891
SLS 2.0	2.7	288	400	276	690
HALF	2.2	480	350	63.7	181.4
SSRF	3.5	432	200	290	1450
TPS	3.0	518.4	400	341	852.7

Wiggler ,26 poles at 1.58T, period of 100mm Power emitted = 4.26kWThis is equivalent to ~2% all the dipole SR

IVU,400 poles at 0.9T, period of 20mm

Power emitted = 4.97kW

This is equivalent to ~2% all the dipole SR

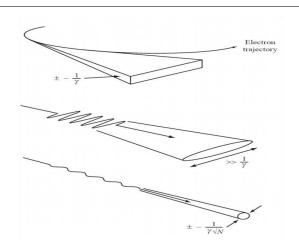
SSRF case

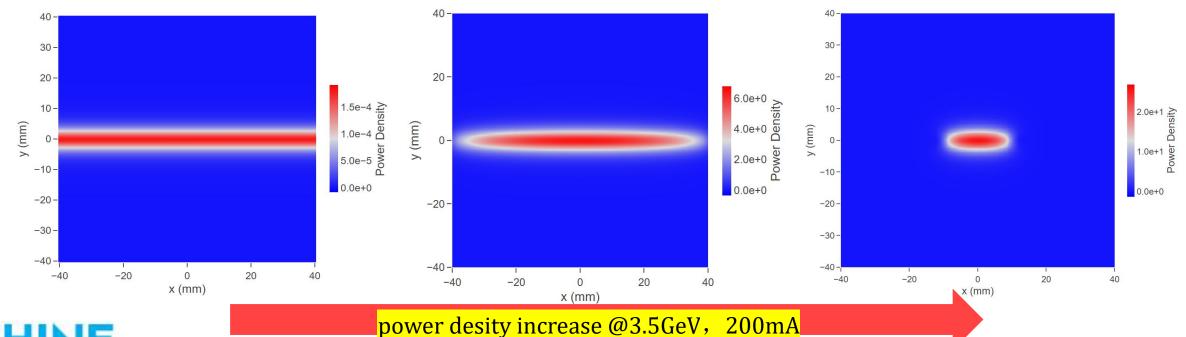


Three basic sources of SR

- DipoleB=1T, L=0.1m
- (Multipole) Wiggler
 B=1T, Period=100mm,L=2m
- Undulator

B=1T,Period=25mm,L=2m







Trajectory of the Electron in sinusoidal field

$$\ddot{x} = \frac{d^2x}{ds^2} = \frac{e}{\gamma m_0 c} (B_y - \dot{y}B_s)$$
$$\ddot{y} = \frac{d^2y}{ds^2} = \frac{e}{\gamma m_0 c} (\dot{x}B_s - B_x)$$

$$B_y(s) = -B_0 \sin\left(\frac{2\pi s}{\lambda_u}\right)$$

$$\dot{x}(s) = \frac{K}{\gamma} \cos\left(\frac{2\pi s}{\lambda_u}\right)$$

$$x(s) = \frac{K}{\gamma} \int \cos\left(\frac{2\pi s}{\lambda_u}\right) ds$$
$$= \frac{K}{\gamma} \frac{\lambda_u}{2\pi} \sin\left(\frac{2\pi s}{\lambda_u}\right) .$$

$$\dot{x}(s) = \frac{K}{\gamma} \cos\left(\frac{2\pi s}{\lambda_u}\right) \qquad K = \frac{B_0 e}{m_0 c} \frac{\lambda_u}{2\pi} = 93.36 B_0 \lambda_u$$

The maximum angular deflection is

 K/γ

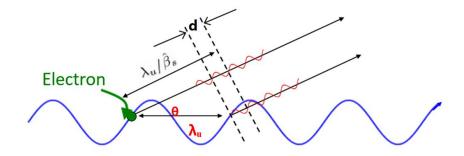
The maximum transverse displacement is

$$\frac{K}{\gamma} \frac{\lambda_u}{2\pi}$$



The Condition for Interference and Undulator equation

For constructive interference between wavefronts emitted by the same electron the electron must slip back by a whole number of wavelengths over one period



Solving for λ we get the **undulator equation** for constructive interference. The wavelength primarily depends on the period and the electron energy but also on **deflection parameter K** and the **observation angle \theta**.

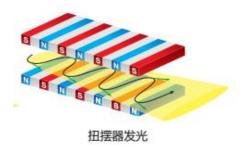
$$\lambda = \frac{\lambda_u}{2n\gamma^2} \left(1 + \frac{K^2}{2} + \theta^2 \gamma^2 \right) \qquad K = \frac{B_0 e}{m_0 c} \frac{\lambda_u}{2\pi} = 93.36 \, B_0 \lambda_u$$



If we can change B_0 we can change λ .

Wiggler Flux

- A Wiggler can be considered a series of dipoles one after the other
- There are two source points per period (two poles per period)
- The flux is simply the number of source points multiplied by the dipole flux for one pole
- The Wiggler has two clear advantages:
 - The spectrum can be set to suit the science need
 - The Flux is enhanced by the number of poles



$$\dot{N} = 2.46 \times 10^{13}$$
 $(2N) EI_b \left(\frac{\epsilon}{\epsilon_c}\right) \int_{\epsilon/\epsilon_c}^{\infty} K_{5/3}(u) du$



Flux density of undulator

the famous undulator equation

$$\lambda = \frac{\lambda_u}{2n\gamma^2} \left(1 + \frac{K^2}{2} + \theta^2 \gamma^2 \right) .$$

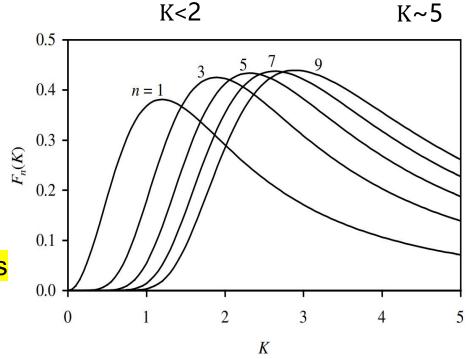
In practical units this gives the number of photons per solid angle per second on-axis for a planar undulator as

$$\frac{d\dot{N}}{d\Omega}\bigg|_{\theta=0} = 1.74 \times 10^{14} \, N^2 E^2 I_b F_n(K)$$

$$F_n(K) = \frac{n^2 K^2}{(1 + K^2/2)^2} \left(J_{(n+1)/2}(Y) - J_{(n-1)/2}(Y) \right)^2$$

There are no even harmonics observed on-axis

For K>5, high harmonic are quite large, mirror heat is heavy, we need suppress





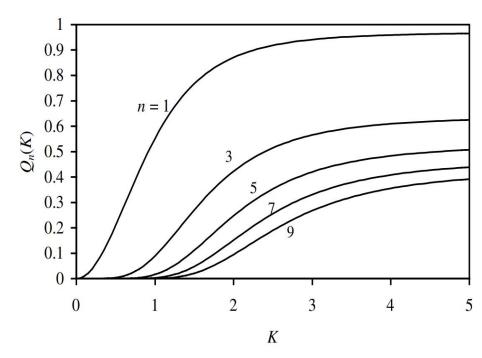
Flux of undulator

$$Q_n(K) = \frac{1 + K^2/2}{n} F_n(K)$$

In practical units of photons per second per 0.1% bandwidth this gives the flux in the central cone as

$$\dot{N} = 1.43 \times 10^{14} \ NI_b Q_n(K)$$

For K<2, high harmonic are quite small, we need more periods N



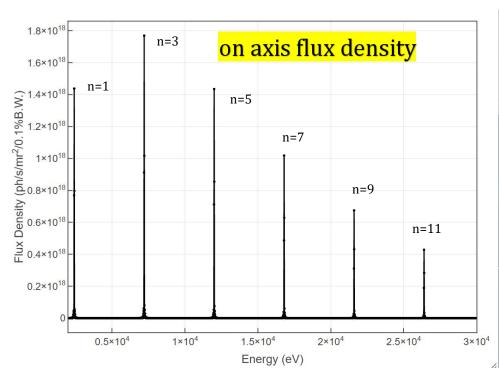


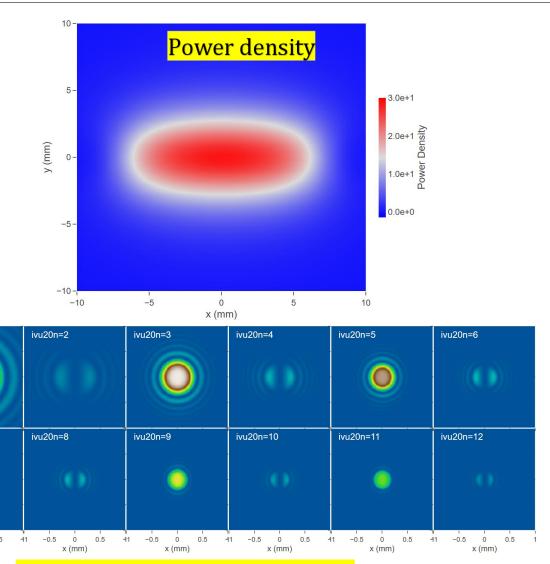
Example K<2, synchrotron radiation

ivu20n=1

ivu20n=7

Period 20mm, B=0.9T,K=1.68 ,3.5GeV,200mA, source point distance 30m



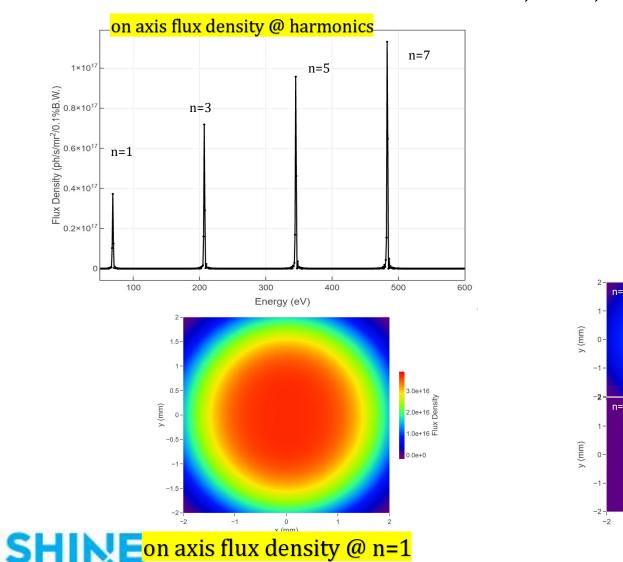


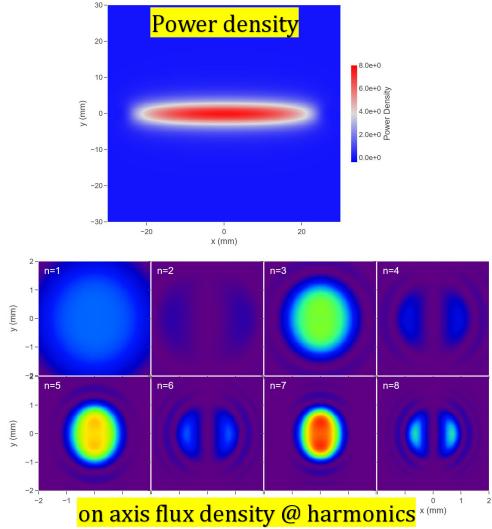


on axis flux density @ harmonics

Example K>5, synchrotron radiation

Period 100mm, B=0.6T,K=5.6,3.5GeV,200mA, source point distance 30m





Harmonic bandwidth

If we calculate at what wavelength destructive interference will occur we can estimate the harmonic bandwidth (width of the harmonic line) to be

$$\frac{\Delta\lambda}{\lambda} \sim \frac{1}{Nn}$$

So, if the undulator has 100 periods then the first harmonic (n = 1) line will have a bandwidth of $^{\sim}1\%$

With a harmonic wavelength of 4 nm, the undulator will provide output between approx 3.98 and 4.02 nm

Bandwidth is inversely proportional to the period numbers, better coherent recieved



Example Angular Flux Density

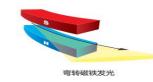
- An Undulator with 50mm period and 100 periods with a 3GeV, 300mA electron beam will generate:
- Angular flux density of **8 x 10¹⁷** photons/sec/mrad²/0.1% bw
- For a dipole with the same electron beam we get a value of $\sim 5 \times 10^{13}$ photons/sec/mrad²/0.1% bw
- The undulator has a flux density ~10,000 times greater than a dipole because it scales with N²
- N is the number of undulator periods

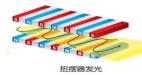


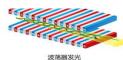
Example Flux

- Undulator with 50mm period, 100 periods
- 3GeV, 300mA electron beam
- Our example undulator has a flux of 4 x 10¹⁵ photons/s/0.1% bandwidth
- The flux is proportional to N

compared with the dipole flux of 10¹³ photons/s/0.1%







$$\dot{N} = 2.46 \times 10^{13} EI_b \left(\frac{\epsilon}{\epsilon_c}\right) \int_{\epsilon/\epsilon_c}^{\infty} K_{5/3}(u) du$$

$$\dot{N} = 2.46 \times 10^{13} \left(2N EI_b \left(\frac{\epsilon}{\epsilon_c} \right) \int_{\epsilon/\epsilon_c}^{\infty} K_{5/3}(u) du \right)$$

$$\dot{N} = 1.43 \times 10^{14} \ N I_b Q_n(K)$$

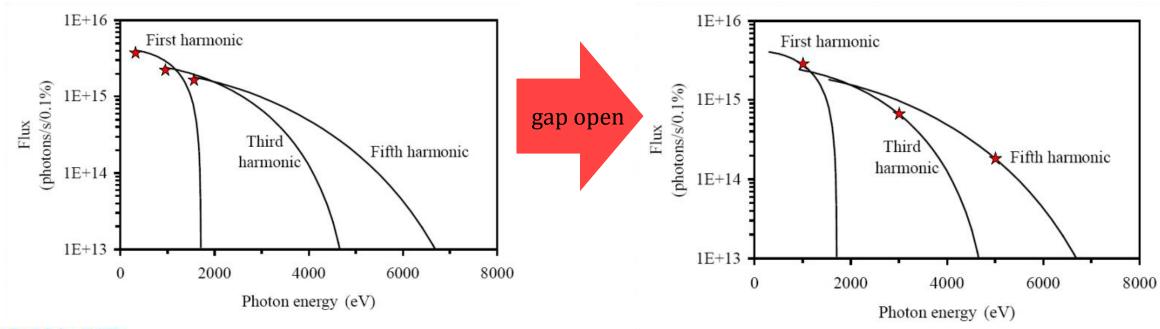


Example Undulator Tuning Curve

Undulator with 50mm period, 100 periods 3GeV, 300mA electron beam

We can tune the wavelength by open the undulator gap

Note: there may be flux@n=5,7 at small gap larger than flux@n=3,5 at bigger gap





Key words for Insertion Devices

$$\lambda = \frac{\lambda u}{2n\gamma^2} \left(1 + \frac{K^2}{2} + \gamma^2 \theta^2 \right)$$

Peak magnetic field: Given the period length, the stronger the magnetic field, the lower the radiation energy

Period length: For goal wavelength, the shorter the period length, the more periods that can be obtained in a limit straight section.

Deflection parameter: for a given K, try to increase B

Flux: The smaller the K value, the weaker the higher harmonics, the higher the energy, the small period IVU requires higher harmonics (requires small phase errors)

The flux is proportional to N

Flux density: The greater the K value, the higher the axial flux density at high-order harmonics (linear polarization mode)

Axial power density: K value large undulator, need to reduce the thermal liability of optical crystals; Filtering required (higher harmonics)



Outline

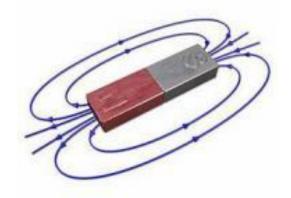
- Insertion devices to generate radiation
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Generating Periodic Magnetic Fields

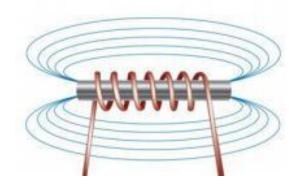
• To generate magnetic fields we can use:

Permanent Magnets



Electromagnets

- Normal conducting
- Superconducting



Both types can also include iron to enhance and shape the field



Permanent Magnets

- Permanent Magnet materials are manufactured so that their magnetic properties are enhanced along a particular axis
- When a magnetic field, B, is applied to a magnetic material each dipole moment tries to align itself with the field direction
- When B is strong enough (at saturation) all of the moments are aligned, overcoming other atomic forces which resist this
- A Permanent Magnet maintains this alignment after the external B is removed

Note: China is the top exporter of permanent magnet materials, with high-quality magnetized blocks gradually dominating the international accelerator market.



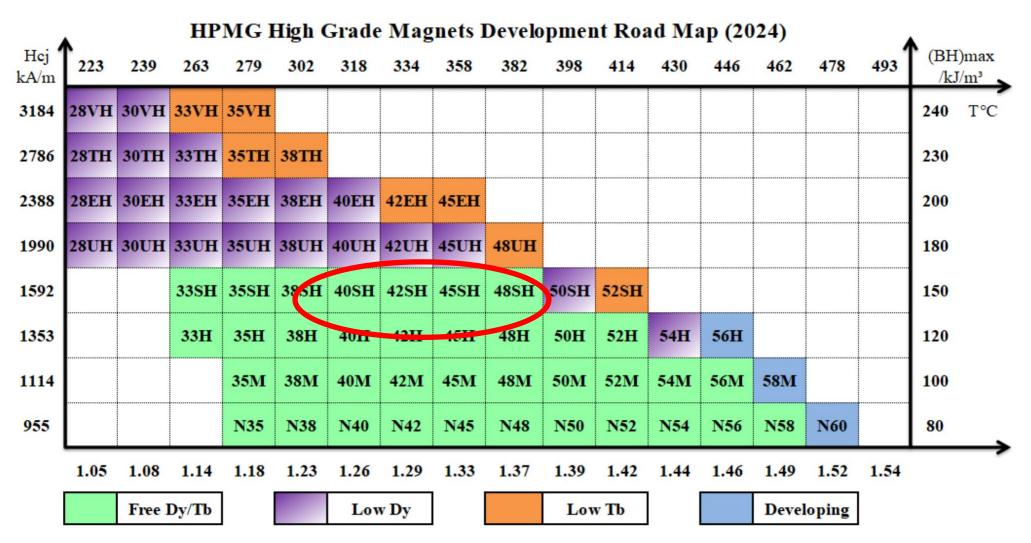
Magnet Materials

Three types of permanent magnet are commonly used for undulators – Samarium Cobalt (SmCo) and Neodymium Iron Boron (NdFeB), a newtype (PrFeB) is also starting to be used for special applications – **these are all very close to ideal in their performance**

	Samarium Cobalt (SmCo)	Neodymium Iron Boron (NdFeB)	Praseodymium iron boron (PrFeB)
Remanent Field	0.85 to 1.1 T	1.1 to 1.4 T @300K about 1.56T @150K	1.3-1.5T @300K 1.6-1.7T @77K
Coercivity	900 to 2400 kA/m	1000 to 2400 kA/m@300K ~5000kA/m@300K	~1500kA/m@300K ~5400kA/m@77K
Relative Permeability	~1.03	~1.05	~1.05
Temperature Coefficient	-0.04 %/。 C	-0.11 %/。 C	-0.11 %/。 C
Max operating temperature	~500K	~400K	<400K

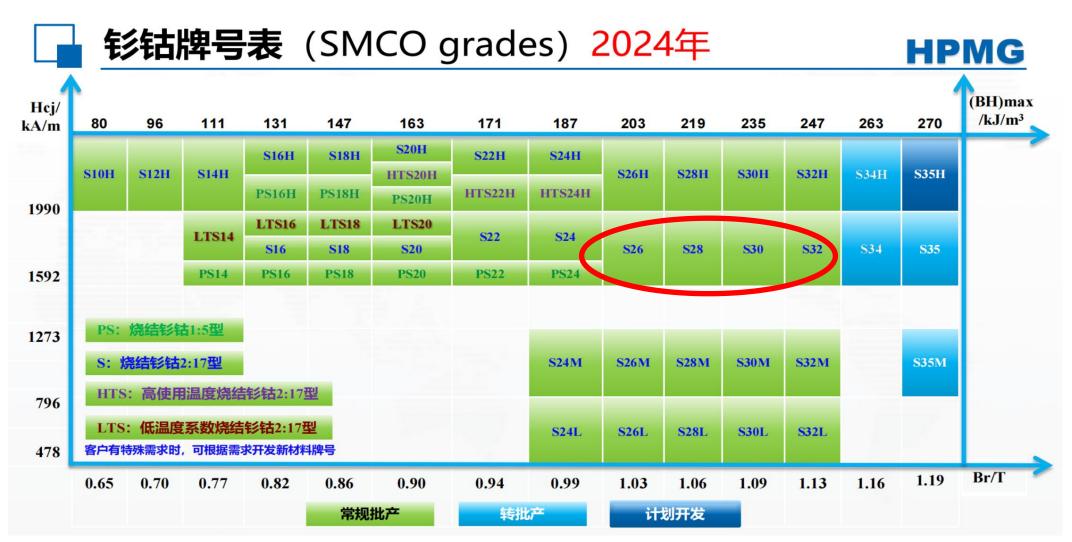


NdFeB magnet





SmCo magnet



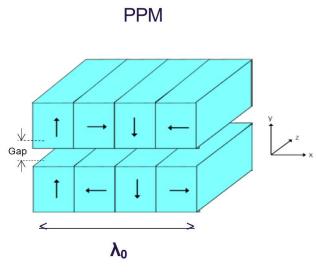


https://www.china-hpmg.com/

Typical magntic array: PPM and Hybrid

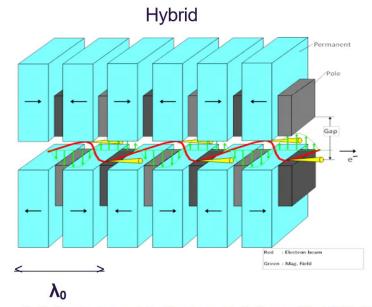
The arrows in the blocks are the field directions generated by each block

Over a full period the arrows have rotated by 360 degree



K. Halbach, NIM 187, (1981) 109

$$B_{y_0} = 1.72 B_r e^{-\pi g/\lambda_u}$$



K. Halbach, Journal de Physique 44, Colloque C1, (1983) 211

$$B_0[g, \lambda_u] = 4.22[T] \exp(-5.08 \times \left(\frac{g}{\lambda_u}\right) + 1.54 \times \left(\frac{g}{\lambda_u}\right)^2)$$



case: LCLS-II、SHINE-U26

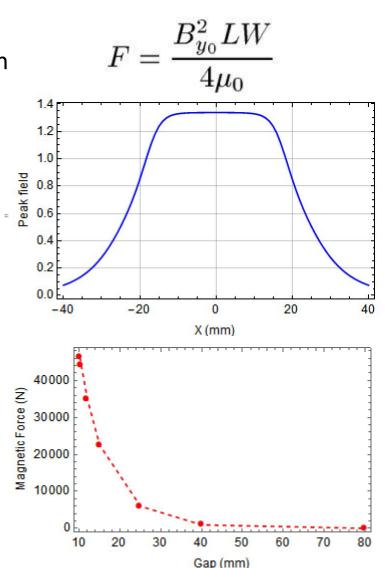
Undulator Forces

 For a sinusoidal field of length L where the vertical field is constantin x over a width W (and zero outside of this width) then the total force between the two arrays is

For SHINE project examples
 4m long undulator,55 mm period hybrid structure and 10.4mm gap undulator with remanent field of 1.28T and a horizontal field width of 35mm

The attractive force between the two arrays is ~50kN

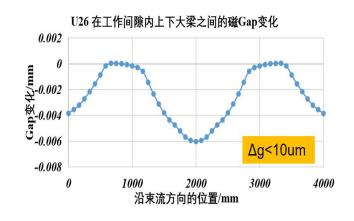
 Note that this force changes rapidly with gap since the field changes exponentially

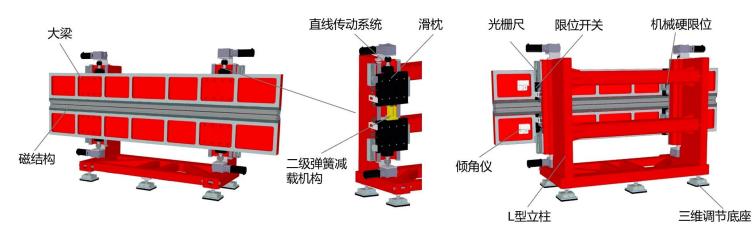




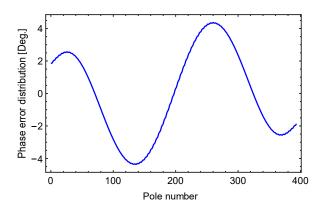
Engineering Issues for all PM Undulators

- Engineering demands are very high:
- Very strong magnetic forces are present during assembly and when complete
- Must achieve very high periodicity
- Arrays must be parallel to µm precision and must stay parallel at all gaps





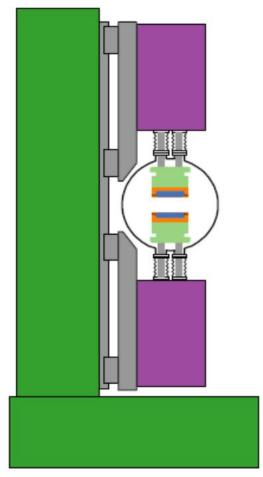




Girder deformance <10 µm, rms phase error ~2.5deg <20 µm, rms phase error ~5deg



Engineering Issues

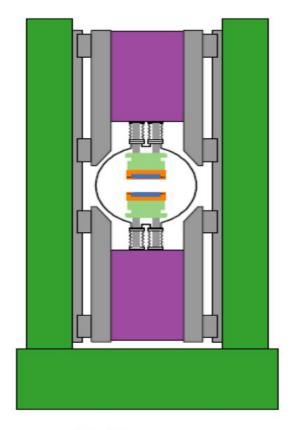


C shape:

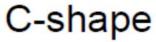
- Best access for magnetic measurements
 & Tuning
- Convenient for installation in storage rings or FELs, especially in air undulator.

H Frame:

- Compact, symmetric support, stable
- but not easy to measurements & tuning



H-Frame





Huge Undulators Project

Although the permanent magnet blocks are themselves physically small, the engineering arrangement needed to generate high quality fields and to change the magnet gap in a precise and controlled way means undulators are large and challenging engineering systems

simple- easy series production- low cost



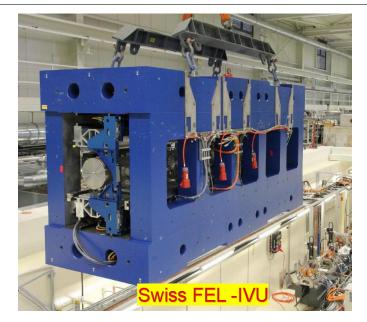
EuXFEL Undulator 5m long, Dessy

LCLS-II Undulator 3.4m long, LBNL

SHINEUndulator 4m long, SARI



H-Frame





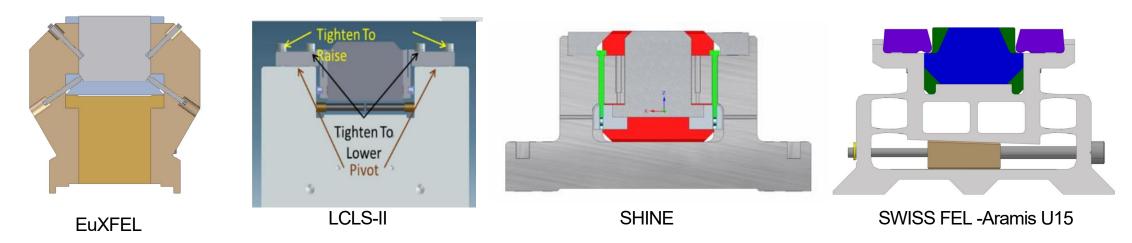






Holder on Magnetic Field Shimming

- Precise magnetic measurements of the undulators are (often) made during assembly as well as of the fully assembled device (over the full gap range)
- Local magnetic field shimming are corrected to ensure the field quality of the undulator meets the specification required, magnetic field intensity/phase error/orbit
- End **shimming** is corrected to fullfill the field integrals requirments, including multipole reduction
- Usually pole or magnet position adjusted within ±0.1mm

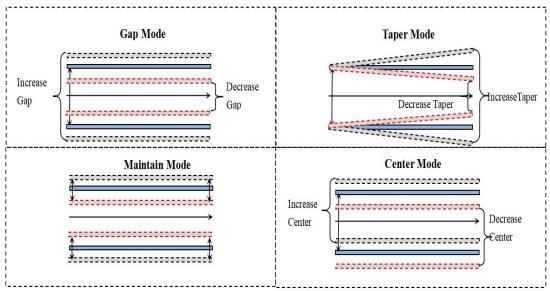


J. Pflüger, H. Lu, T. Teichmann NIM A429 (1999), 368

Although shimming is a time consuming task, it is a very important step, since the magnetic errors will be significantly reduced.

Motion Control for IDs

- ➤ Motion control function
- four motion control modes
- Local and remote control function
- Position protection (soft limit, hard limit, electromechanical,
- photoelectric)
- Emergency stop function
- Communication interface based on Modbus TCP
- Other interfaces (temperature monitoring and interlock)
- Torque protection





- Gap mode, adjustment of gap of magnetic pole
- Taper mode, adjustment of deviation between the entrance gap and the exit gap and keeping it within a certain range.
- Center mode, adjustment of magnetic pole height.
- Inclined mode

The movements of the four motors are completely independent and can be operated independently

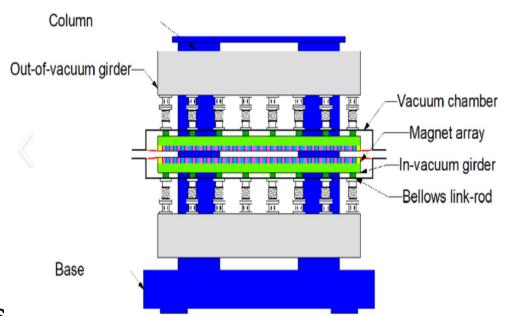


Assembly magnet into Vacuum chamber

- The minimum magnet gap limits the peak field of an undulator
- The magnet gap is determined by the needs of the electron beam
- In practice this is set by the vacuum chamber
- ➤ If an electron beam needs 5mm of vertical space For in air undulator
 - ➤ The vacuum chamber walls are 0.5mm thick
 - With an allowance for mechanical tolerances of 0.5mm
 - The minimum magnet gap will be at least 5+0.5*2+0.5*2=7mm (LCLS-II case\SHINE case)

So 2 mm is effectively wasted as far as the magnet is concerned

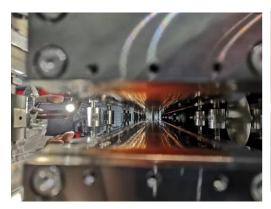
Better option is to put the undulator inside the vacuum chamber





In Vacuum Undulators

- Decrease minimum gap to 3-6mm
- coating of magnets to reduce outgassing
 Ti+TiN ion plating of NdFeB or SmCo magnets
- Pick high coercive magnetic material (bakeout less than 120°)
- NiCu sheet to reduce image current heating
- (20 Ni + 50 Cu)
- water cooled RF-fingers
 Heat load from synchrotron radiation and beam impedance







IVUs have been extensively utilized in the third-generation synchrotron radiation light sources since 1990s and FELs from 2005



Sirius IVU at SSRF



In-Vacuum undulator for FELs

Facility	日本 SACLA	瑞士 Swiss-FEL	上海 SXFEL-SBP
length (m)	5	4	4
period (mm)	18	15	16
number	277	266	243
gap (mm)	3.5	3.2	3.6
peak field(T)	1.57	1.27	1.22
Magnet	NdFeB	NdFeB+Dy	SmCo











SXFEL IVUs



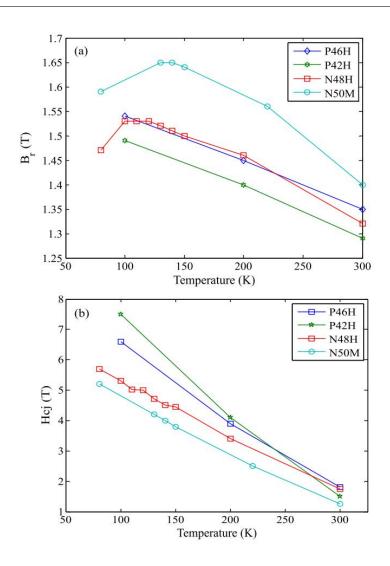
Cryogenic Undulators (CPMUs)

PM Magnetisation increases

- As temperature decreases, coercivity increases even more – selection of stronger grades of PM possible
- The intrinsic coercivity increases also which helps with radiation resistance and allowsselection of stronger grades
- Better magnetic performance, better vacuum performance because cold, better radiation damage resistance

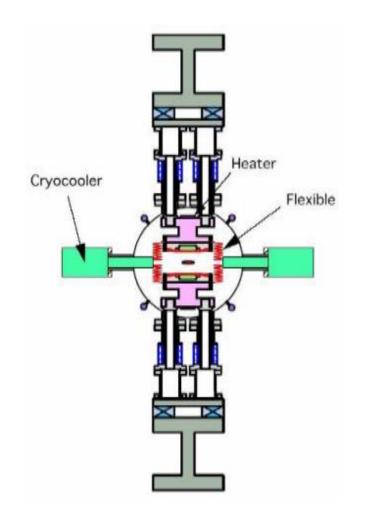
PrFeB is now the material of choice:

- Basically an in-vacuum device with cryogenic cooling attached
- It is strong (B_r up to ~1.7T) and works at 77K which is a very easy temperature to achieve and maintain with liquid nitrogen
- Need higher temperature stability requirements compared to NdFeB



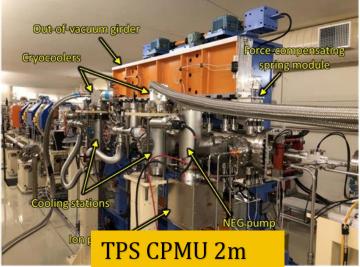


Cryogenic PM undulators











G. 1. TPS-CPMU, CU15 installed in the TPS storage ring.

Measurement facilities for IDs

1. Hall probe system (on-fly measurement)

probe: SENIS H3A, Resolution 0.02GS granite scan range in z 6500/5000mm, 300mm in x /y Field strengh/ phase error/ trajectory

2. Flipping coil

coil length: Max 5m, coil width 2.8mm, repeatability 3Gs.cm First and second field integral, kick value for undulator

3. Capacitance sensor

can be integrated in the Hall probe scan system precision: ~2μm Measured magnetic gap

4. Optical displacement meter

can be integrated in the Hall probe scan system precision: $\sim 1 \mu m$





Hall ptobe scan system



flipping coil system



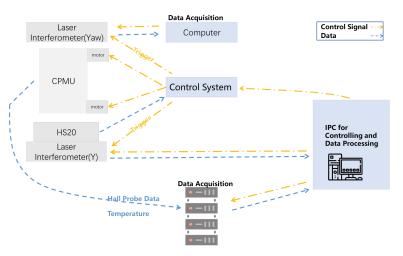
Capacitance sensor

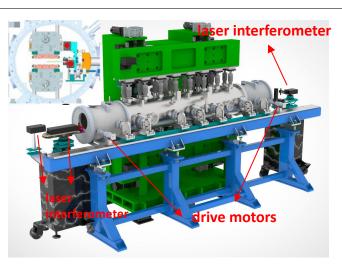


Optical displacement meter



CPMU Magnetic field measurement system





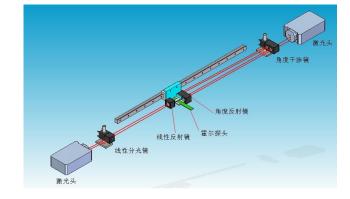


Figure 1: System Structure Diagram

Figure 2: System 3D Diagram

Figure 4: Optical System for Deformation Measurement of Magnetic Measurement Rail inside the Vacuum Chamber

- The test system consists of a deformation measurement optical system, a data acquisition system, and a motion control system.
- Three laser systems are used: a laser interferometer measures the angular deviation (Yaw) and straightness in the Y-direction of the linear guide rail, while a laser distance measurement system is used for beamline positioning in the Z-direction.
- The head and tail motors and magnetic fluid drive the rollers inside the extended chamber, pulling the steel wire rope to move the Hall probe along the linear guide rail. This setup allows for equidistant triggering to obtain Hall probe voltage data, angular deviation, and Y-direction straightness.

Elliptical Undulator Example: APPLE-2

This is the most popular elliptical undulator It consists of **four standard** PPM arrays

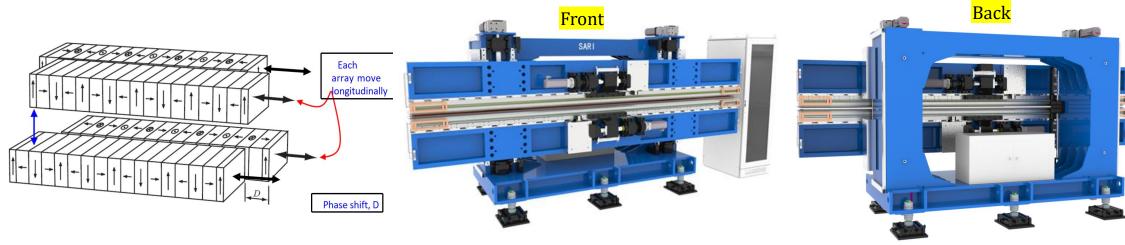
Adjust gap to tune K

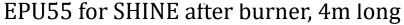
Each magnet array can move longitudinally

-----From two to four, polarization modes at arbitrary angles

$$B_x = B_{x0} \cos(\frac{2\pi}{\lambda_1} z)$$

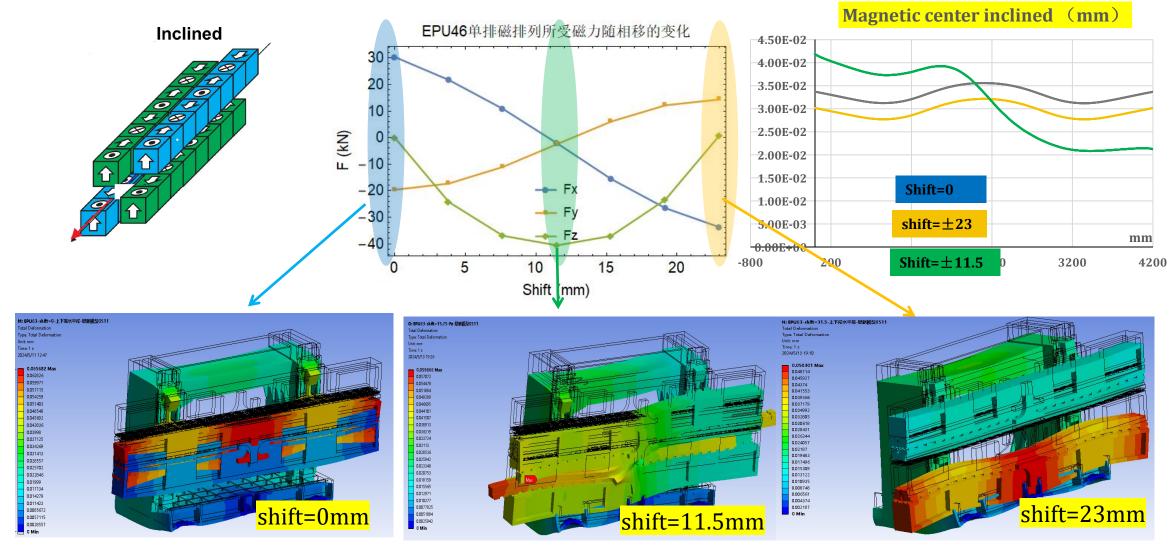
$$B_{y} = B_{y0} \sin(\frac{2\pi}{\lambda_{1}}z) -$$







Strong mechanical for EPU Inclined-MODE





EPU with High K, long length

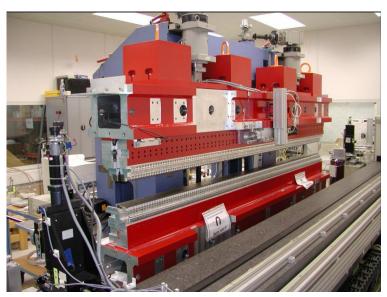
• Length: >4m

• Height: >2.3m

• Weight: >15 tons



TPS EPU, 4m long



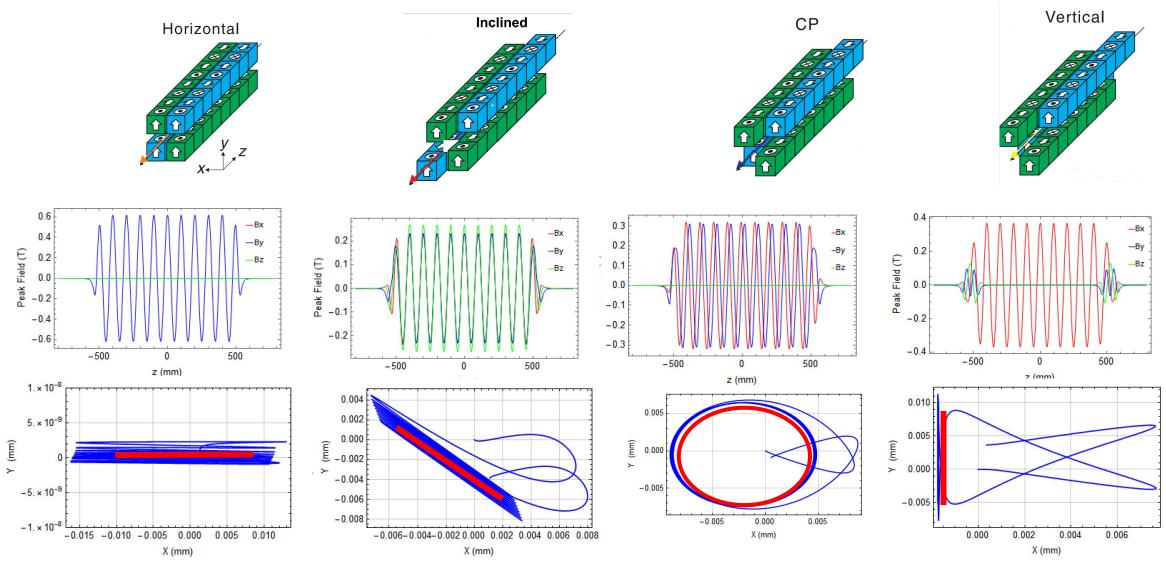
PETRA, 5m long



HALF, 4.2m long



Example Trajectories: 3.5GeV, period 100mm APPLE-II EPU





Trajectories viewed head on – as the observer sees them

APPLE-II: K = 5.6



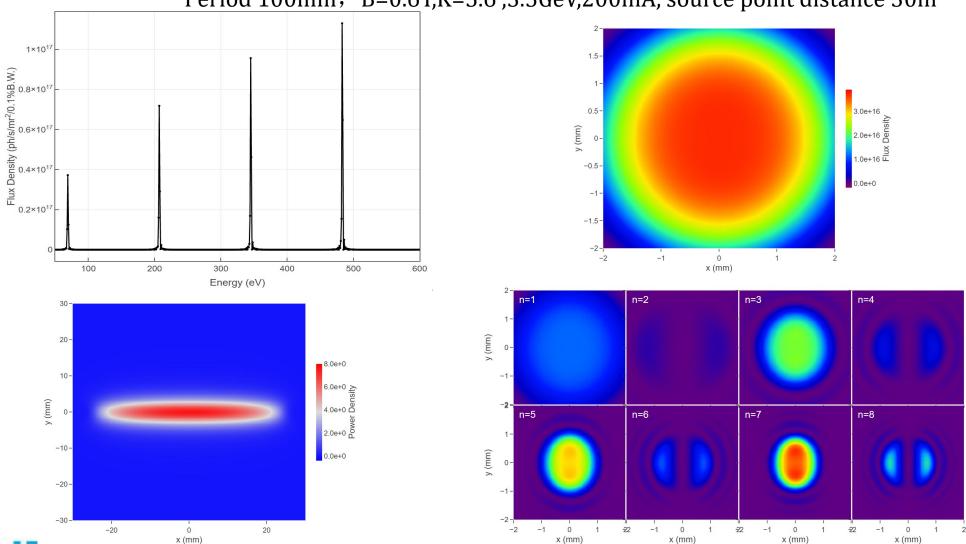




Figure-8 undulator: same K

$$B_x = -B_{x0}\sin(\frac{\pi}{\lambda_u}z)$$

$$B_{y} = B_{y0} \sin(\frac{2\pi}{\lambda_{u}}z)$$

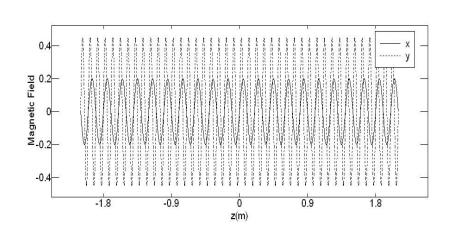
$$x' = -\frac{e\lambda_u B_{y0}}{2\pi mc\beta_z} \cos \frac{2\pi}{\lambda_u} z$$

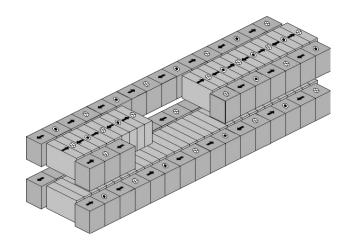
$$y' = \frac{e\lambda_u B_{x0}}{\pi m c \beta_z} \cos \frac{\pi}{\lambda_u} z$$

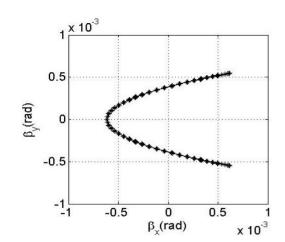
$$x = -\frac{eB_{y0}}{mc\beta_z} (\frac{\lambda_u}{2\pi})^2 \sin \frac{2\pi}{\lambda_u} z \quad \widehat{\mathbb{g}}$$

$$y = \frac{eB_{x0}}{mc\beta_z} (\frac{\lambda_u}{\pi})^2 \sin \frac{\pi}{\lambda_u} z$$

$$\beta_z = \frac{\beta}{\sqrt{1 + {x'}^2 + {y'}^2}} \approx \beta$$







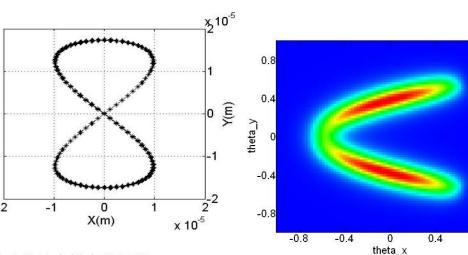


图 2.4 Figure-8 波荡器速度及轨迹在横向的投影



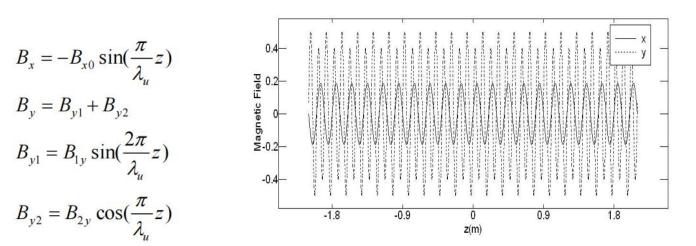
AFigure-8 : same K

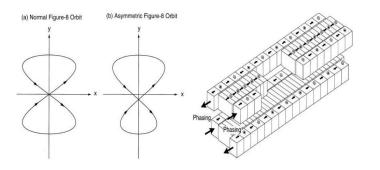
$$B_x = -B_{x0}\sin(\frac{\pi}{\lambda_u}z)$$

$$B_y = B_{y1} + B_{y2}$$

$$B_{y1} = B_{1y} \sin(\frac{2\pi}{\lambda_y}z)$$

$$B_{y2} = B_{2y} \cos(\frac{\pi}{\lambda_u} z)$$





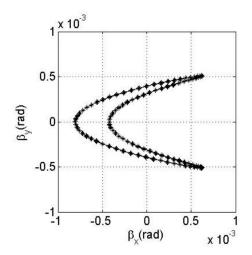
$$x' = -\frac{e}{mc\beta_z} \left(\frac{\lambda_u}{2\pi}\right) \left[B_{1y} \cos \frac{2\pi}{\lambda_u} z - 2B_{2y} \sin \frac{\pi}{\lambda_u} z \right]$$

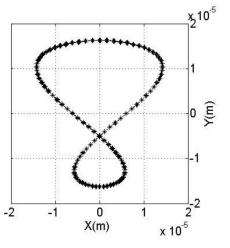
$$y' = \frac{eB_{x0}}{mc\beta_z} \left(\frac{\lambda_u}{\pi}\right) \cos \frac{\pi}{\lambda_u} z$$

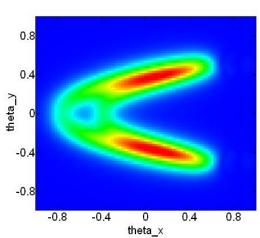
$$x = -\frac{e}{mc\beta_z} \left(\frac{\lambda_u}{2\pi}\right)^2 \left[B_{1y} \sin \frac{2\pi}{\lambda_u} z + 4B_{2y} \cos \frac{\pi}{\lambda_u} z \right] \quad \widehat{\mathbb{E}}_{\mathbf{z}}$$

$$y = \frac{eB_{x0}}{mc\beta_z} (\frac{\lambda_u}{\pi})^2 \sin \frac{\pi}{\lambda_u} z$$

$$\beta_z = \frac{\beta}{\sqrt{1 + {x'}^2 + {y'}^2}} \approx \beta$$









PERA undulator: same K

$$B_{x} = -B_{x0} \sin(\frac{2\pi}{\lambda_{u}}z)$$

$$B_{y} = B_{y1} + B_{y2}$$

$$B_{y1} = \frac{3}{2}B_{y0} \cos(\frac{2\pi}{2\lambda_{u}/3}z)$$

$$B_{y2} = \frac{1}{2}B_{y0} \cos(\frac{2\pi}{2\lambda_{u}}z)$$

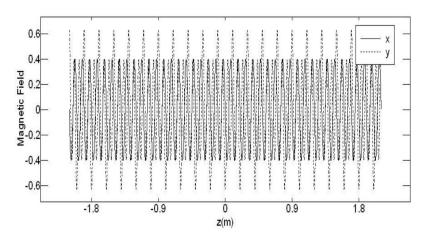
$$x' = \frac{eB_{y0}}{mc\beta_z} \left(\frac{\lambda_u}{2\pi}\right) \left[\sin \frac{3\pi}{\lambda_u} z + \sin \frac{\pi}{\lambda_u} z \right]$$

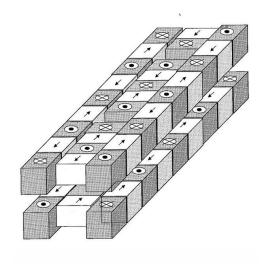
$$y' = \frac{eB_{x0}}{mc\beta_z} \left(\frac{\lambda_u}{2\pi}\right) \cos \frac{2\pi}{\lambda_u} z$$

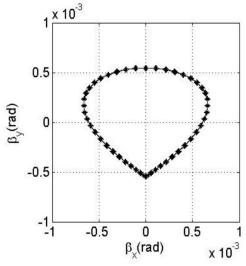
$$x = -\frac{eB_{y0}}{mc\beta_z} \left(\frac{\lambda_u}{2\pi}\right)^2 \left[\frac{2}{3} \cos \frac{3\pi}{\lambda_u} z + 2 \cos \frac{\pi}{\lambda_u} z \right]$$

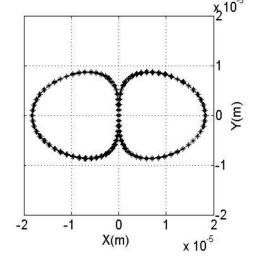
$$y = \frac{eB_{x0}}{mc\beta_z} \left(\frac{\lambda_u}{2\pi}\right)^2 \sin \frac{2\pi}{\lambda_u} z$$

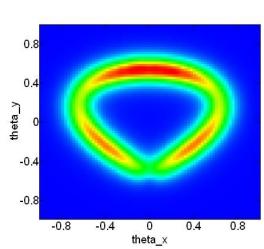
$$\beta_z = \frac{\beta}{\sqrt{1 + x'^2 + y'^2}} \approx \beta$$





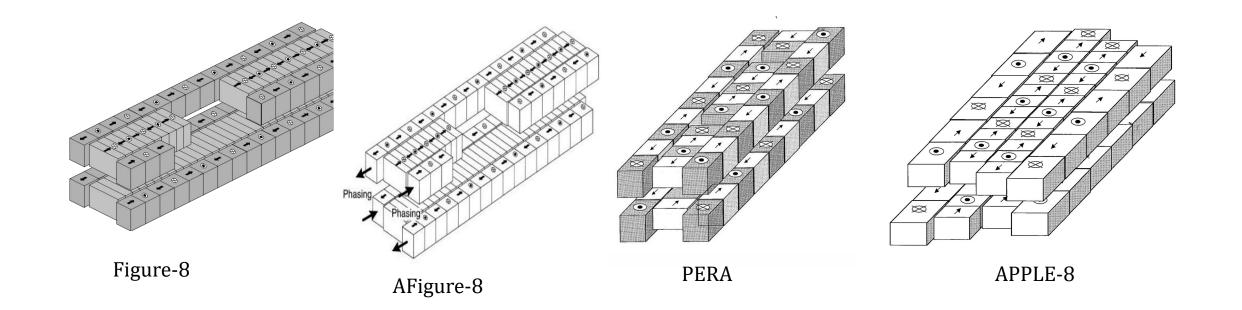








APPLE-8



General expression APPLE-8

$$B_{x} = B_{x10} \cos(\frac{2\pi}{\lambda_{1}}z) + B_{x20} \cos(\frac{2\pi}{\lambda_{2}}z)$$

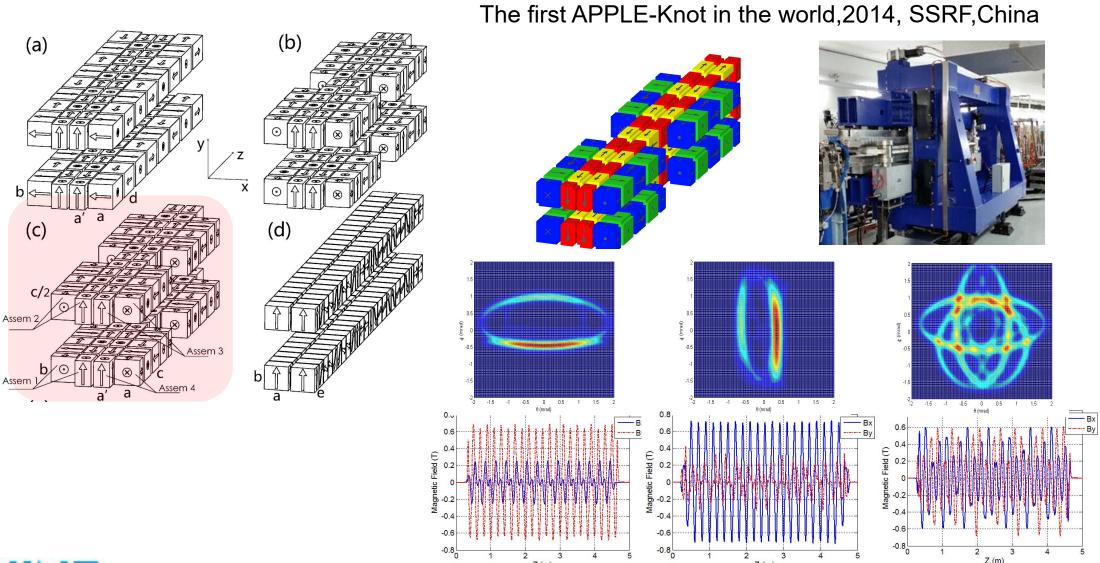
$$B_{y} = B_{y10} \sin(\frac{2\pi}{\lambda_{1}}z) - B_{y20} \sin(\frac{2\pi}{\lambda_{2}}z)$$





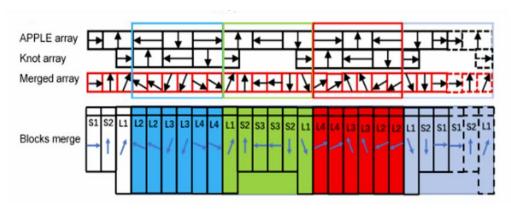


APPLE-Knot



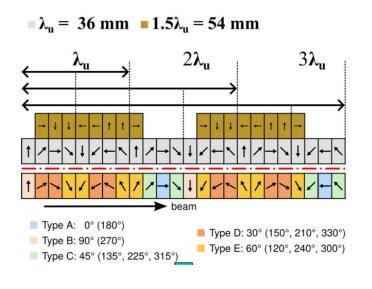


New Knot *Merged four arrays*

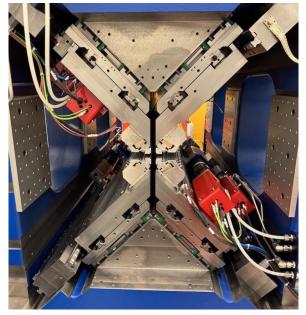


APPLEII+Knot HEPS, China





APPLEX+Knot SLS 2, PSI





Mango wiggler at HEPS

$$B_x(z) = B_0 \sin\left(\frac{2\pi z}{\lambda_{ux}}\right), \qquad \lambda_{ux} = \frac{L}{N_u \pm (1/4)},$$

$$B_{y}(z) = B_{0} \sin \left(\frac{2\pi z}{\lambda_{uy}}\right), \qquad \lambda_{uy} = \frac{L}{N_{u}}.$$

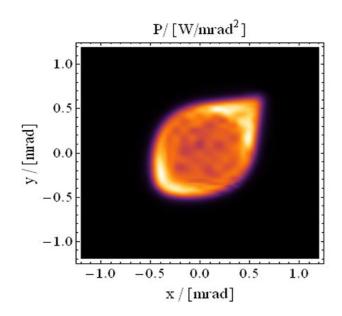
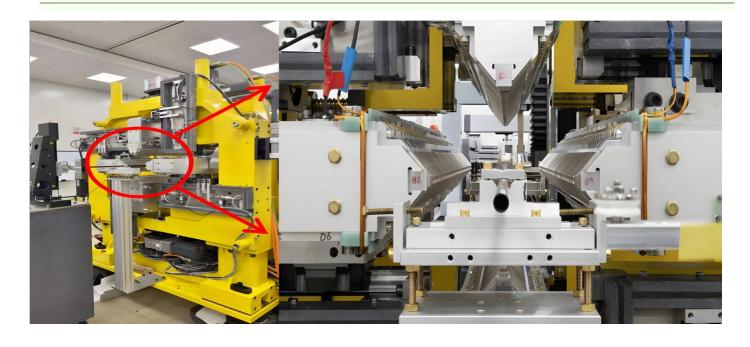


Table 1. Parameters of the Mango wiggler designed for HEPS.

Peak magnetic field strength, B_0 1.0 T (0.2–1.0 T adjustable for the tapered mode)

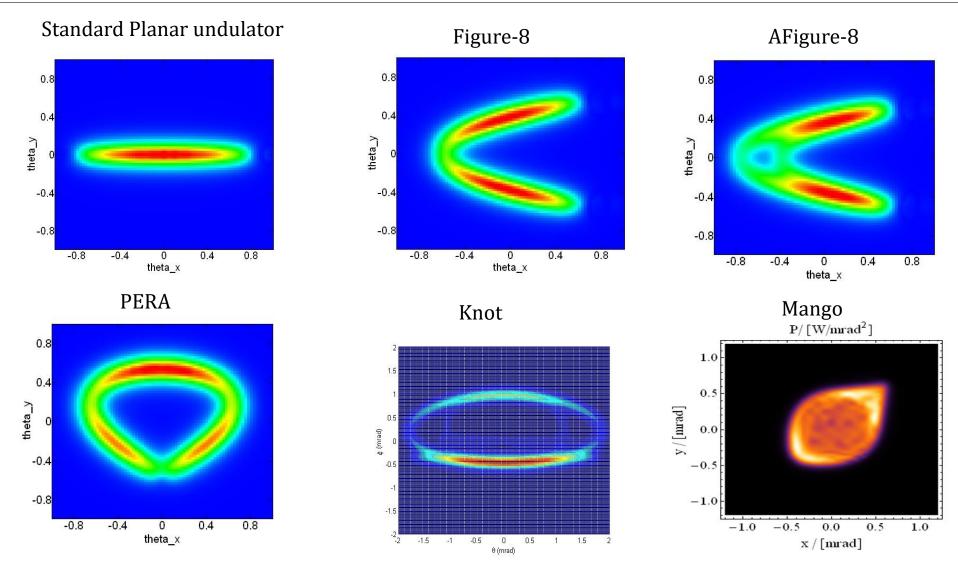
Period lengths, $\lambda_{ux}/\lambda_{uy}$ 50.70 mm/50 mm

Period, N_{ux}/N_{uy} 17.75/18



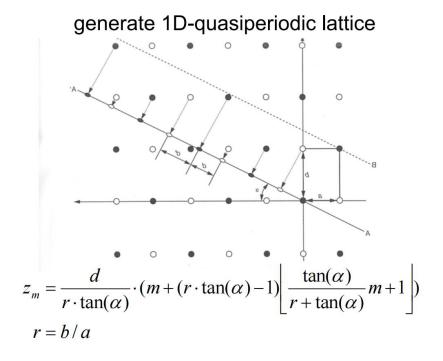


Power density distribution





Quasi-periodic Undulators (S. Sasaki)



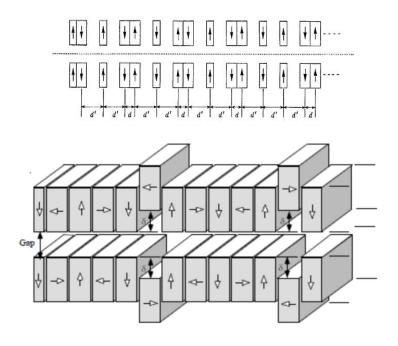


图 3.6 ESRF 准周期结构示意图[11]

Purpose

- The electron beam trajectory changes when passing through a quasi-periodic undulator, resulting in quasi-periodic oscillations.
- The traditional high-order harmonic generated shift to irrational position.
- The irrational harmonic radiation can be filtered out using a monochromator.



QEPU Quasi-period example

EU12.5 Quasi-period at ELETTRA

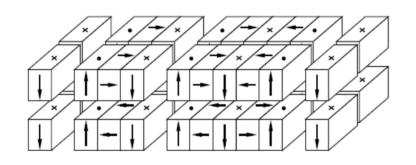
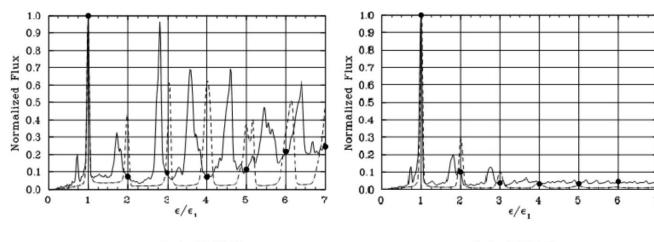


图 3.9 ELETTRA 准周期 APPLE-II 型椭圆波荡器结构示意图[12]



(1) 线极化

(2) 圆极化

DEPU Quasi-period at low-EPU, SSRF 2013

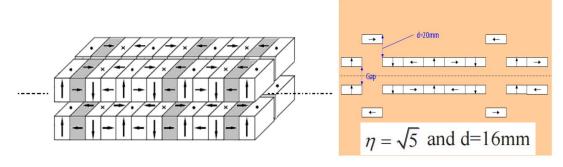
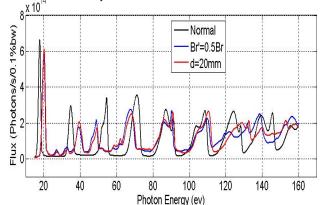


图 3.38 两种不同准周期方案的磁结构示意图







Outline

- Insertion devices to generate radiation
- Types of Insertion devices
- Undulators torwards the future
- Try to design a undulator?



Double Period Undulator--extended energy range

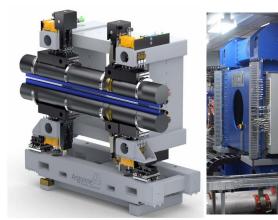
Double Undulator

Source point remains constant.

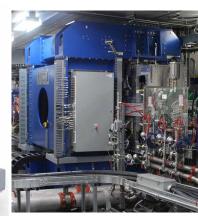
Revolver undulator: SPring-8, APS2014, Dessy 2018

DEPU: SSRF 2013,CLS2016

DPU: SXFEL 2018



Proposed by BESSY_III





At SHINE project

First prototype 2022.

Double period undulator line, 2025

(10.1109/TASC.2023.3346838)



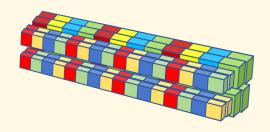




Force compasation technology for DPU

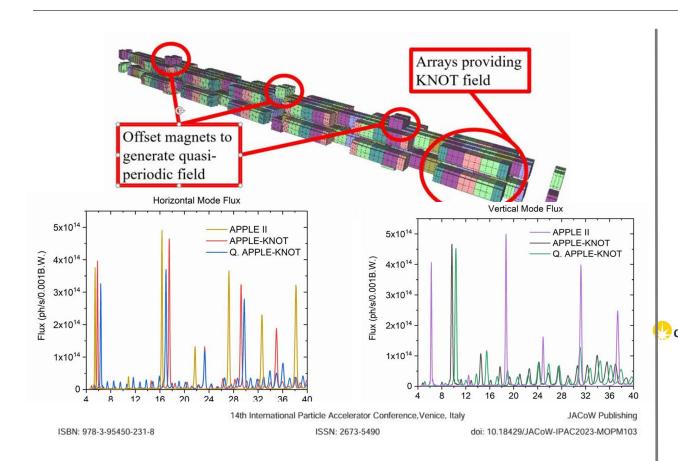
A prospective device to bring two in-vacuum APPLE II arrays side by side.

Practical development starting 2026.





APPLE-II+Knot+Quasi: Multi-functional



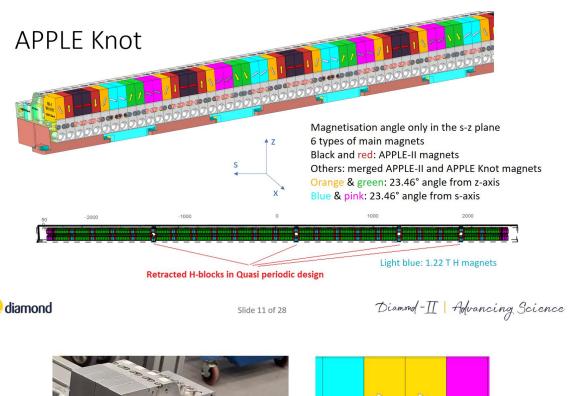
UNDULATORS FOR BESSY III

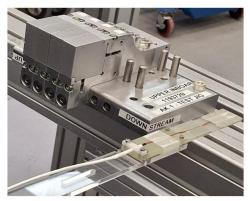
E. C. M. Rial[†], A. Meseck¹, J. Bahrdt, J. Bakos, S. Gäbel, S. Gottschlich, S. Grimmer, K. Karimi, C. Kuhn, F. Laube, A. Rogosch-Opolka, S. Schäfer, M. Scheer, M. Strehlke, P. Volz¹

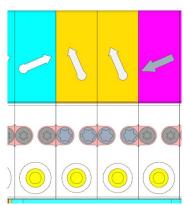
Helmholtz Zentrum Berlin, Berlin, Germany

¹also at Johannes Gutenberg University Mainz, Germany









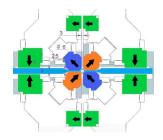
Force Compensation for high field EPU

Length: 4 m
Period: 68mm
Peak field: 1.5T

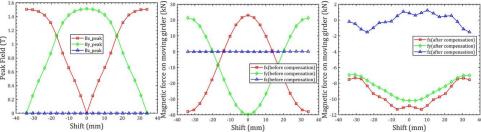
Vertical Gap range: 3.2--150mm

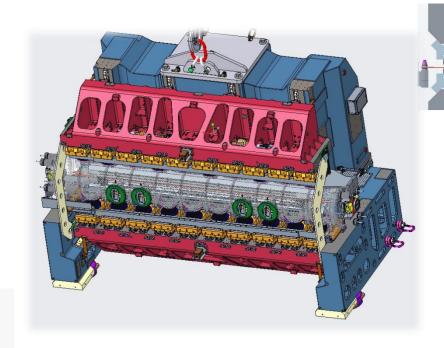
Qiaogen, Z. (2018). Novel Undulators Developed at SINAP. Synchrotron Radiation News, 31(3), 18-23. https://doi.org/10.1080/08940886.2018.1460170





Front. Phys., 27 June 2023 Sec. Interdisciplinary Physics Volume 11 - 2023 | https://doi.org/10.3389/fphy.2023.1174620





9th International Particle Accelerator Conference IPAC2018, Vancouver, BC, Canada JACoW Publishing doi:10.18429/JACoW-IPAC2018-THPMF031

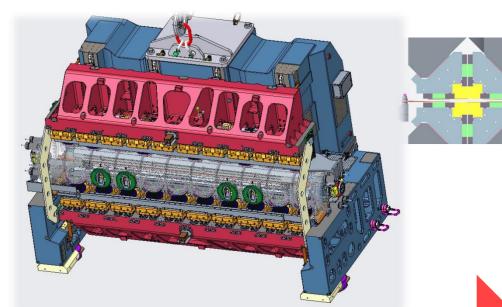
IN-VACUUM APPLE II UNDULATOR

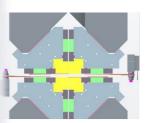
J. Bahrdt, W. Frentrup, S. Grimmer, C. Kuhn, C. Rethfeldt, M. Scheer, B. Schulz, Helmholtz-Zentrum Berlin, 12489 Berlin, Germany

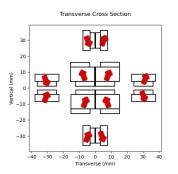
J. Bahrdt, S. Grimmer, in *proc. SRI 2018*, Taipeh, Taiwan, to be published in AIP conference proceeding



Force Compensation for In vacuum EPU







Cryogenic APPLE: Mechanical Design



Magnets

Girder

shimming

Force Compensation Design

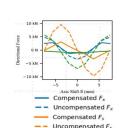
informs mechanical design

Two part keeper mounted against on-girder positioning features for

easier assembly and

Central cooling channel

E. Rial – Insertion Devices for Future Light Sources Workshop – Taipei, Taiwan



TUPM064: Cryogenic **APPLE Undulator** Development at Helmholtz-Zentrum Berlin E. Rial et al

Mechanical Simulations

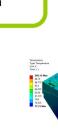
Deflection of keeper and support

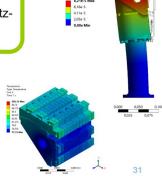
columns under residual magnet forces simulated and fall within

acceptable ranges

Thermal Simulations

Steady state thermal simulations show <1K variation near the magnet



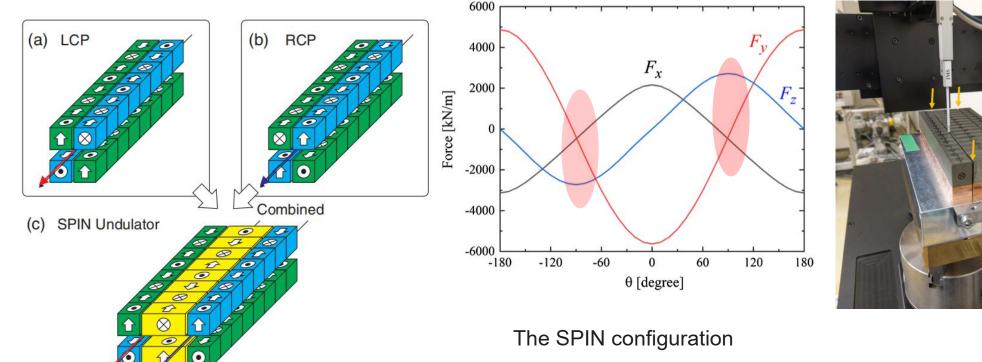


Cryogenic

J. Bahrdt, S. Grimmer, in proc. SRI 2018, Taipeh, Taiwan, to be published in AIP conference proceeding



In-vacuum SPIN-EPU



Undulator configuration for helicity switching in in-vacuum undulators

Ryota Kinjoo* and Takashi Tanaka RIKEN SPring-8 Center, 1-1-1, Koto, Sayo-cho, Sayo-gun, Hyogo, 679-5148, Japan

(Received 12 December 2019; accepted 12 February 2020; published 21 February 2020)

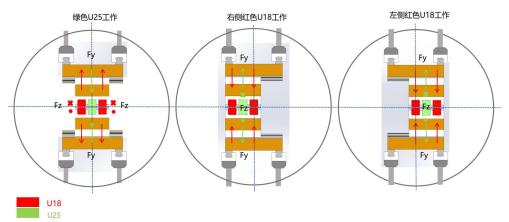
•DOI: 10.1103/PhysRevAccelBeams.23.020705

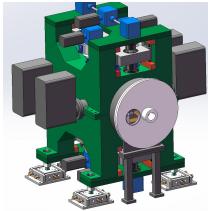
- It is well compatible with IVUs because the phasing operation is not necessary and the magnetic force can be much weaker than conventional undulators.
- It can achieve LC /RC and Horizontal polarization
 - Maybe best solution for IVEPU



Compact IVU

Magnetic force compensation by double or triple periods

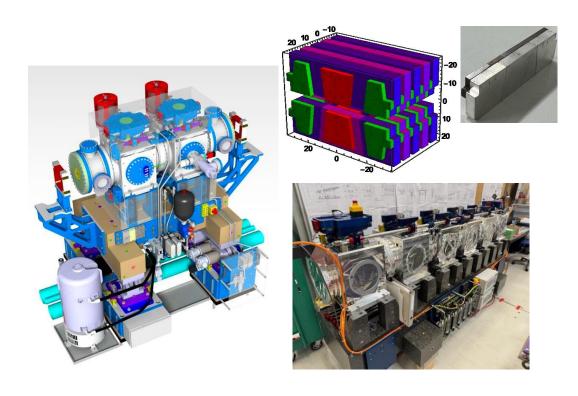




SRI2024,A double-period in-vacuum undulator moving in three directions

SHINE

Soldering of magnetized Permanent Magnets

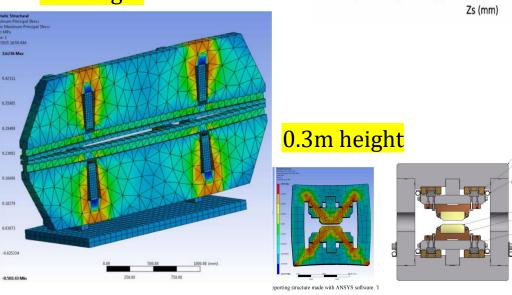


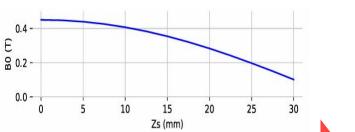
IPAC2025, Sebastian C. Richter – Paul Scherrer Institute PSI: Novel APPLE X knot & Compact Modular in-Vacuum Undulators for SLS 2.0

Fix Gap Compact PMU

APU: When the phase between up arrays and down arrays changes, the magnetic field will also change

2m height



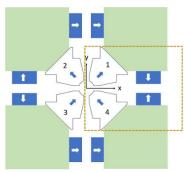


PU to EPU



Elettra Fix gap EPU





APS Fix gap EPU, based on force compensation

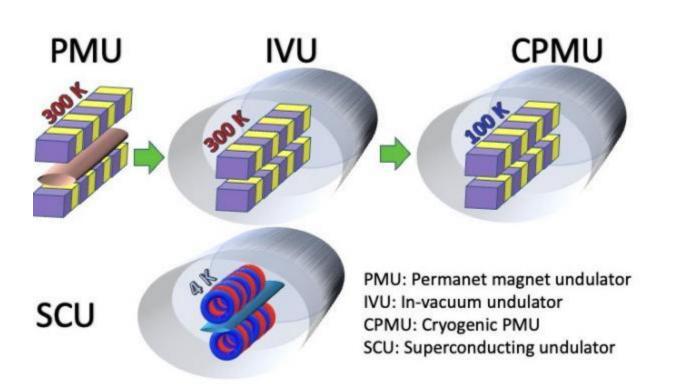
Construction of CHESS Compact Undulator magnets at Kyma

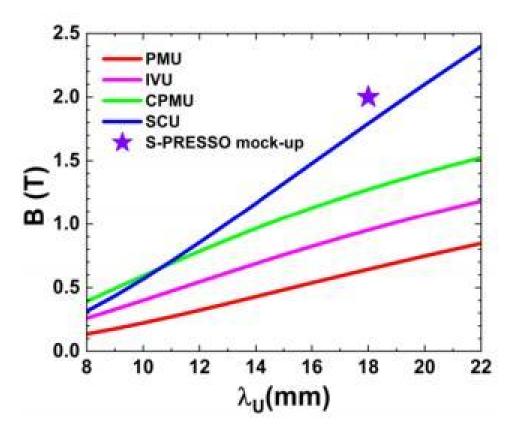
Alexander B. Temnykh^a, Aaron Lyndaker^a, Mirko Kokole^{b*}, Tadej Milharčič^b, Jure Počkar^b, Raffaella Geometrante^c

^aCornell University, Ithaca, NY, 14850, USA; ^bKyma Tehnologija, Sežana, Slovenia; ^cKyma Srl, Trieste, Italy

Compact without gap tunable

Superconducting Undulator towards FEL







Why Superconducting Undulator

A superconducting undulator (SCU) is an insertion device that generates periodic magnetic fields using superconducting coils.

Higher Peak Field

Larger gap for same period; shorter period for same gap as PMUs

Broad Spectral Coverage with SC coil current

- Fast, precise tuning of field strength
- Wide spectral range coverage through flexible field adjustment.
- Compact Design, Reduces overall device size and construction costs.

Low sensitivity to radiation damage, comparing to PMs

$$\lambda = \frac{\lambda_U}{2 n \gamma^2} \left(1 + \frac{K^2}{2} + \gamma^2 \theta^2 \right)$$

$$K = \frac{e}{2\pi mc} B_0 \lambda_U = 0.9336 B_0[T] \lambda_U[cm]$$

LTS undulator

- Operate at 1.8 K 4.2K
- Mature technology (Facility-grade)

HTS undulator

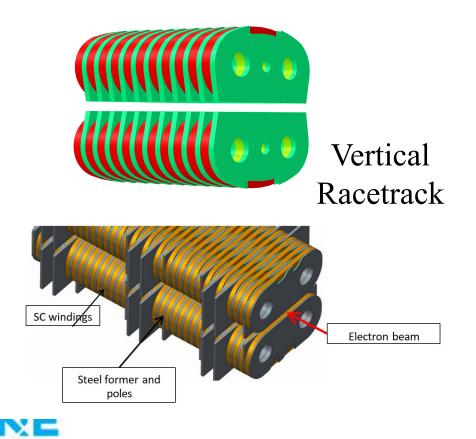
- Operate at 20 K 70 K
- Frontier research (Lab-scale)



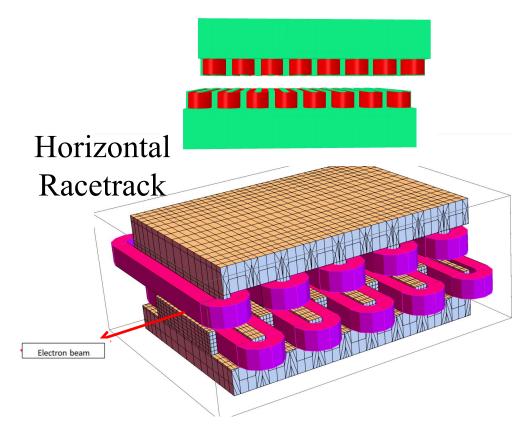
Magnet Design of SCU

The standard solution is very simple – currents flowing perpendicular to the beam axis with iron poles

The challenge is the engineering







Operating SCUs in Storage

TABLE VI. Parameters of storage ring SCUs which have been installed and operated successfully. Gap is the beam chamber vertical aperture.

Facility	$\lambda_u \text{ [mm]}$	N	Gap [mm]	B_{peak}
KIT synchrotron	14	100	8	0.3
KIT synchrotron	15	100.5	7	0.73
KIT synchrotron	20	74.5	7	1.18
APS	16	20.5	7.2	0.8
APS	18	59.5	7.2	0.97
APS	31.5	38.5	8	0.4









SCUs for FEL

EXFEL: 5 modules (2m+2m)

Prototype work, 1 module finished on 2026

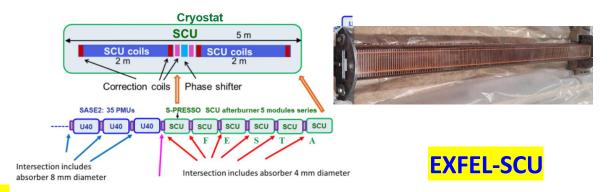
LCLSII: 1 modules (2m+2m)

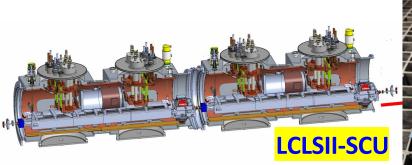
Prototype work, uncertain

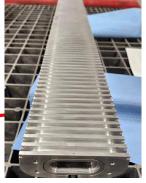
SHINE: 42 modules (from 4m prototype to 3m+3m)

4 m prototype 2025, 3+3 in technical design

Lab.	Period length	Magnetic Length	Magnetic gap	Vacuum gap	Undulator field B0
KIT ²⁰¹⁶	15mm	1.5m	8mm	7mm	0.73 T
APS ²⁰²³	18mm	1.075m	9.8mm	7.2mm	0.97 T
IHEP ²⁰²³	15mm	1.5m	9.5mm	6.5mm	0.5T
SHINE ²⁰²³	16mm	<mark>4m</mark>	5(<mark>4</mark>)mm		1.58T
EuXFEL	18mm	(2+2)m	6mm	5mm	1.82T
APS-U	16.5mm	(1.9+1.9)m	8mm	6.3mm	1.1T







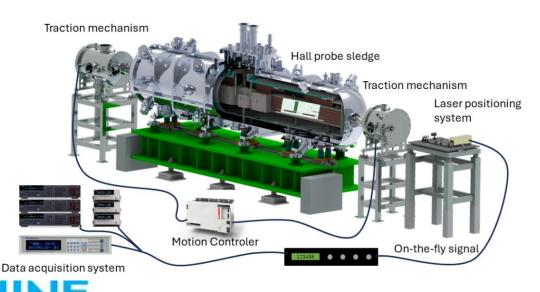


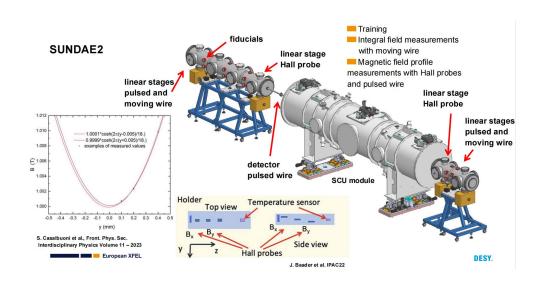




Superconducting Undulators Challenges

- The field quality has to be as good as existing undulators and most SC undulator groups do not use any field shimming so the engineering tolerances need to be very precise, pole height\coil dimension\period length\...
- Field measument for >2m long SCU is still a challenge, small gap, low tem, high peak field
- Beam heat load and superconducting thermal insulation remain challenges for the stable operation of FEL SC.





EXFEL-SCU prototype

Try to design an undulator?

Need: What kind of machine/beam/radiation would do the job?

- e-beam energy and current
- photon energy range
- minimum gap limit
- space limit
- photons
- polarizaton

$$\lambda = \frac{\lambda_u}{2n\gamma^2} \left(1 + \frac{K^2}{2} + \theta^2 \gamma^2 \right)$$

$$K = \frac{B_0 e}{m_0 c} \frac{\lambda_u}{2\pi} = 93.36 B_0 \lambda_u$$

PPM
$$B_{y_0} = 1.72 \, B_r e^{-\pi g/\lambda_u}$$

Hybrid

$$B_0[g, \lambda_u] = 4.22[T] \exp(-5.08 \times \left(\frac{g}{\lambda_u}\right) + 1.54 \times \left(\frac{g}{\lambda_u}\right)^2)$$



$$B = \left(0.28052 + 0.05798 \cdot \lambda_U - 0.0009 \cdot \lambda_U^2 + 5.10^{-6} \cdot \lambda_U^3
ight) \cdot \exp\left(-\pi \cdot \left(rac{g}{\lambda_U} - 0.5
ight)
ight)$$



Summary

- Undulator is the key component of SR and FEL.
 - The core of the undulator generate a periodic magnetic field to produce high performance SR
 - Type of excitation: permanent magnet and electromagnetic
- Permanent magnet undulators: PPM type and hybrid type are relatively popular, more than 95% of the current use.
- Invacuum---low temperature---superconducting
 - IVUs can achieve short periods and small gaps, so as to obtain a high peak magnetic field.
 - CPMU can increase the peak magnetic field by 10-20%.
 - Superconducting undulator is a hot topic in recent years, with strong magnetic field, challenge in low stability and measurement. But a good future.
- Compact EPU with short period, strong magnetic field, on axis power density suppression is the main development direction.

